

Title (en)

THIN FILM STRAIN SENSORS BASED ON INTERFEROMETRIC OPTICAL MEASUREMENTS

Title (de)

DÜNNSCHICHTDEFORMATIONSSSENSOREN FÜR INTERFEROMETRISCH-OPTISCHEN MESSUNGEN

Title (fr)

CAPTEURS DE CONTRAINTE A FILM MINCE POUR MESURES OPTIQUES INTERFEROMETRIQUES

Publication

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Application

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Abstract (en)

[origin: WO0012960A1] The invention relates to polymeric/semiconductor thin film strain gauges comprising visible light from spectrometer (10) which is directed onto a thin film passive sensor (12) having a transparent glass substrate (14) and a laminated construction in succession from the substrate (14), of a polyimide layer (18a), a polysiloxane layer (16a) filled with alumina particles, a polyimide layer (18b) and a polysiloxane layer (16b) filled with alumina particles.

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G01B 9/02

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